ABSTRACT

A NOVEL SPACER TECHNOLOGY FOR MAKING LIQUID-CRYSTAL-ON-SILICON DISPLAYS WITH ALIGNMENT POSTS

Two new methods for the formation of an improved liquid-crystal-on-silicon display are described, in which the device structure is enhanced by the photolithographic building of alignment posts among the mirror pixels of the microdisplay. These two methods are:

Photolithographic Alignment Posts Formed in Active Area - wherein a photographic method forms patterned oxide spacers or alignment posts in the active area of the device structures.

Photolithographic Alignment Posts Formed in Peripheral Sealant - wherein said alignment posts are deposited by the photolithographic process in the area of the ring sealant/glue for the glass top cover.

(FIGURE 1 IS SUGGESTED FOR PUBLICATION)